That which is claimed is:

- 1. A method for use during manufacture of a flat-panel display from a glass substrate comprising:
 - providing a vacuum processing system having:
- a transfer chamber adapted to transfer the substrate under vacuum conditions, the transfer chamber having a sidewall with a plurality of facets formed therein;
- a domed lid mounted on the transfer chamber and adapted to form an airtight seal with the transfer chamber;
- at least a first process chamber coupled to the transfer chamber via a first of the plurality of facets, wherein the first facet is adapted to provide access to and isolation between the transfer chamber and the first process chamber; and
 - at least a first load lock chamber coupled to the transfer chamber via a second one of the plurality of facets, wherein the second facet provides access to and isolation between the transfer chamber and the first load lock chamber; and
 - employing the vacuum processing system during manufacture a flat-panel display from the substrate.
- The method of claim 1 wherein employing the vacuum processing system during
 manufacture of a flat-panel display includes:

loading the substrate into the first load lock chamber;

reducing the pressure in the first load lock chamber to substantially match a pressure in the transfer chamber; and

transferring the substrate from the load lock chamber to the first processing chamber.

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- 3. The method of claim 2 further comprising cooling the substrate in the transfer chamber.
- 4. The method of claim 1 further comprising viewing the substrate via one or more windows formed within the domed lid.
 - 5. The method of claim 4 wherein the one or more windows are oriented perpendicularly

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relative to the substrate.

- 6. The method of claim 1 further comprising: coupling a sensor internally on the lid; and
- 5 employing the sensor to determine a position of the substrate within the transfer chamber.
 - 7. The method of claim 6 further comprising correcting the position of the substrate.